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Document Number (Citation)

TSMC-00-511

Reference Number

10/689, 430

Applicant

Filing Date

Hong-Miao Chen et al.

10/26/03

Drawn At U.S.

10/26/03

## U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	ALSO DATE IF APPROPRIATE
TA	60551064/25/00		Grier et al.	359	566	2/3/98
	59531669/14/99		Shikama	359	837	11/21/97
	568910911/18/97		Schutze	250	251	1/13/94
	56208574/15/97		Weetall et al.	435	7.1	6/7/95
	52454669/14/93		Burns et al.	359	296	10/8/91
	50791691/7/92		Chu et al.	436	172	5/22/90
	48938861/16/90		Ashkin et al.	350	1.1	9/17/87
	55127454/30/96		Finer et al.	250	251	3/9/94
	38085504/30/74		Ashkin	331	94.5	1/24/72
TA	613983110/31/00		Shivashankar et al.	424	8205	5/28/98

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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